

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:) Confirmation No.: 9270
Koichiro TANAKA et al.) Examiner: Hung D. Nguyen
Serial No. 10/582,013) Group Art Unit: 3742
Filed: June 7, 2006)
For: LASER IRRADIATION METHOD,)
IRRADIATION APPARATUS, AND)
METHOD FOR FABRICATING)
SEMICONDUCTOR DEVICE)

AMENDMENT AND RESPONSE TO ELECTION REQUIREMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Specification begin on page 1 of this paper.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 11 of this paper.